Application Number 09 Docket Number (Optional) 005606/ETCH/SILICO Applicant(s) INFORMATION DISCLOSURE CITATION Anisul Khan et al. (Use several sheets if necessary) Group Art Unit Filing Date Filed Herewith Unassigne U.S. PATENT DOCUMENTS FILING DATE EXAMINER SUBCLASS CLASS DATE NAME DOCUMENT NUMBER INITIAL IF APPROPRIATE 7 438 4/1/86 Suzuki et al. 4,579,623 428 161 3/26/96 Laermer et al. 5,501,893 FOREIGN PATENT DOCUMENTS Translation CLASS SUBCLASS REF DOCUMENT NUMBER DATE COUNTRY YES NO H01L 21 306 4/18/90 **EPO** 0 363 982 A2 H01L 21 306 8/5/92 **EPO** 0 497 023 A1 OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) I.W. Rangelow, "High-resolution tri-level process by downstream-microwave RF-biased etching," SPIE, Vol.1392, Advanced Techniques for Integrated Circuit Processing (1990), pp. 180-184. 1 SA K. Tsujimoto et al., "A New Side Wall Protection Technique in Microwave Plasma Etching Using a Chopping Method", Abstracts of the 18th (1986 International) Conference on Solid State Devices and Materials, Tokyo, 1986, pp. 229-232. 2 SA DATE CONSIDERED **EXAMINER** 6103 EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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